

AMENDMENT TRANSMITTAL LETTER				Docket No. 12088/019001	
Application No. 10/500,317-Conf. #9863	Filing Date June 28, 2004	Examiner R. Zervigon	Art Unit 1792		
Applicant(s): Shinichi Kawasaki et al.					
Invention: PLASMA FILM FORMING SYSTEM					
TO THE COMMISSIONER FOR PATENTS					
Transmitted herewith is an amendment in the above-identified application.					
The fee has been calculated and is transmitted as shown below.					
CLAIMS AS AMENDED					
	Claims Remaining After Amendment	Highest Number Previously Paid	Number Extra Claims Present	Rate	
Total Claims	10	- 59 =	0	x 50.00	0.00
Independent Claims	1	- 3 =	0	x 210.00	0.00
Multiple Dependent Claims (check if applicable) <input type="checkbox"/>					
Other fee (please specify):					
TOTAL ADDITIONAL FEE FOR THIS AMENDMENT:					0.00
<input checked="" type="checkbox"/> Large Entity <input type="checkbox"/> Small Entity					
<input checked="" type="checkbox"/> No additional fee is required for this amendment.					
<input type="checkbox"/> Please charge Deposit Account No. _____ in the amount of \$ _____. A duplicate copy of this sheet is enclosed.					
<input type="checkbox"/> A check in the amount of \$ _____ to cover the filing fee is enclosed.					
<input type="checkbox"/> Payment by credit card.					
<input checked="" type="checkbox"/> The Director is hereby authorized to charge and credit Deposit Account No. <u>50-0591</u> as described below. A duplicate copy of this sheet is enclosed.					
<input checked="" type="checkbox"/> Credit any overpayment.					
<input checked="" type="checkbox"/> Charge any additional filing or application processing fees required under 37 CFR 1.16 and 1.17.					
/Jonathan P. Osha/ Jonathan P. Osha Attorney/Agent Reg. No.: 33,986 OSHA · LIANG LLP 1221 McKinney St., Suite 2800 Houston, Texas 77010 (713) 228-8600				Dated: <u>August 4, 2008</u>	

Docket No.: 12088/019001
(PATENT)

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of:
Shinichi Kawasaki et al.

Application No.: 10/500,317

Confirmation No.: 9863

Filed: June 28, 2004

Art Unit: 1792

For: PLASMA FILM FORMING SYSTEM

Examiner: R. Zervigon

REPLY UNDER 37 C.F.R. § 1.111

Ms Amendment
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Dear Sir:

In response to the Office Action dated May 2, 2008, please reconsider this application in view of the following.